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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.
09/019,087	02/05/98	ENOMOTO	H TIJ-24816

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EXAMINER	
PEREZ RAMOS, V	
ART UNIT	PAPER NUMBER

1765

17

DATE MAILED: 02/12/01

Please find below and/or attached an Office communication concerning this application or proceeding.

Commissioner of Patents and Trademarks

Office Action Summary

Application No.

09/019,087

Applicant(s)

ENOMOTO ET AL.

Examiner

Vanessa Perez-Ramos

Art Unit

1765

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --
Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136 (a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133).
- Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 17 November 2000.
- 2a) ☒ This action is **FINAL**. 2b) ☐ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-11 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 1-11 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claims _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on _____ is/are objected to by the Examiner.
- 11) ☐ The proposed drawing correction filed on _____ is: a) ☐ approved b) ☐ disapproved.
- 12) ☐ The oath or declaration is objected to by the Examiner.

Priority under 35 U.S.C. § 119

- 13) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some * c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
2. ☐ Certified copies of the priority documents have been received in Application No. _____.
3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).
- * See the attached detailed Office action for a list of the certified copies not received.
- 14) ☐ Acknowledgement is made of a claim for domestic priority under 35 U.S.C. § 119(e).

Attachment(s)

- 15) ☐ Notice of References Cited (PTO-892)
- 16) ☐ Notice of Draftsperson's Patent Drawing Review (PTO-948)
- 17) ☒ Information Disclosure Statement(s) (PTO-1449) Paper No(s) _____
- 18) ☐ Interview Summary (PTO-413) Paper No(s). _____
- 19) ☐ Notice of Informal Patent Application (PTO-152)
- 20) ☐ Other: _____

Art Unit: 1765

DETAILED ACTION

Claim Rejections - 35 USC § 103

1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

2. Claims 1-11 are rejected under 35 U.S.C. 103(a) as being unpatentable over Tsuji (U.S. 5,514,625) in view of Harari (U.S. 4,933,739).

In regard to claims 1-3, Tsuji teaches a method of manufacturing a semiconductor device comprising: forming an insulating film over a substrate (col. 5, lines 7-10), forming a first mask on said insulating film (col. 5, line 24) and forming a resist film on the first mask film (col. 5, line 18). This resist film serves as a mask during the etching process (col. 5, lines 32-35) to form an opening (col. 5, lines 29-31), which is followed by the formation of trenches on said insulating film (col. 5, lines 26-28). Furthermore, Tsuji teaches the formation of a second mask film (col. 5, line 46) and its use as an etching mask during the formation of connecting holes (col. 5, lines 44-50). Tsuji also teaches the formation of a wiring layer by burying an electroconductive material in the trenches (col. 7, lines 19-23). Furthermore, Tsuji discloses that the second mask is located in the same position where the next opening would be later etched. Given the fact that the second opening in Applicant's invention is etched through the sidewalls covered with the second

Art Unit: 1765

mask film, it is the Examiner's position that Tsuji's disclosure about the position of the openings etched after deposition of the second mask read on Applicant's limitation of "the second mask film covering sidewalls and a bottom of the trenches".

Unlike the claimed invention, Tsuji does not disclose the removal of the first and second mask films, nor does he disclose the trenches having sidewalls.

It would have been obvious to one of ordinary skill in the art at the time the invention was made to modify Tsuji by removing the first and second mask films during the semiconductor manufacturing process, since it is well known in the art of semiconductor manufacturing that masks are meant to be removed after etching and other processes.

Furthermore, although Tsuji does not explicitly disclose that his trenches have sidewalls, it is well known to any skilled in the art that a trench has sidewalls, as it has sides and the "walls" that form its sides are its sidewalls. Evidence can be found by referring to any one of Tsuji's Fig. 4-8, where it can be noted that the trench formed has sidewalls. Furthermore, Harari explicitly discloses the fact that a trench has sidewalls (col. 24, line 30). Therefore, and as stated above, even though Tsuji does not explicitly disclose that his trenches have sidewalls, this is an inherent property of a trench, as evidenced by Harari.

In regard to claims 4, 7 and 9, these claims differ from Tsuji by specifying various materials for the insulating film. It would have been obvious to one of ordinary skill in the art at the time the invention was made to modify Tsuji by using different materials to form the insulating

Art Unit: 1765

film in anticipation of an expected result, since the use of such different materials is well known in the art of semiconductor manufacturing.

In regard to claims 5-6, 8 and 10-11, these claims differ from Tsuji by specifying that the holes are in contact with the lower electrodes in the capacitors of the memory cells, and by disclosing that capacitors are set for storing information. It is the Examiner's position that these are conditions well known in the semiconductor art, and that it would have been obvious to modify Tsuji by disclosing the above-mentioned information.

Response to Arguments

3. Applicant's arguments filed 11/17/00 have been fully considered but they are not persuasive.

In response to Applicant's argument that Tsujidoes not teach the formation of a resist film on the first mask film, and later the formation of a second mask film on the substrate, but rather on a reticle, Applicant is directed to Tsuji's col. 5, lines 7-50, where Tsuji discloses forming an insulating film over a substrate (col. 5, lines 7-10), forming a first mask on said insulating film (col. 5, line 24) and forming a resist film on the first mask film (col. 5, line 18). This resist film serves as a mask during the etching process (col. 5, lines 32-35) to form an opening (col. 5, lines 29-31), which is followed by the formation of trenches on said insulating film (col. 5, lines 26-28). Furthermore, Tsuji teaches the formation of a second mask film (col. 5, line 46) and its use as an etching mask during the formation of connecting holes (col. 5, lines 44-50). The presence or

Art Unit: 1765

absence of the "reticle" that Applicant refers to does not affect Tsuji's rendering of the claimed invention obvious.


4. **THIS ACTION IS MADE FINAL.** Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire **THREE MONTHS** from the mailing date of this action. In the event a first reply is filed within **TWO MONTHS** of the mailing date of this final action and the advisory action is not mailed until after the end of the **THREE-MONTH** shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than **SIX MONTHS** from the mailing date of this final action.

5. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Vanessa Perez-Ramos whose telephone number is (703) 306-5510.

VPR

February 8, 2001


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